

Ion etching unit NIKA-130



Specialized vacuum unit constructed specially for customers product based on vacuum post "NIKA-2012". Water-cooled chamber with viewing windows, chamber size $\varnothing 500 \times 400$ mm.

Technological devices :

- ion source IBS-125;
- SOVA automatic recirculated water supply system
- **стол для размещения обрабатываемых деталей**

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Layout and characteristics



IBS-125 – Ion source
Flange mounted version



SOVA
automatic recirculated water supply
system

Parameters

| | |
|----------------------------------|--|
| Supply voltage | 380V +10-15 % |
| Power | 11,2 kW |
| Pumping devices | Backing vacuum pump ISP-250 Turbomolecular pump KyKy |
| Time to reach ultimate vacuum | no more than 2 h. |
| Number of gas injection channels | 2 |
| Dimensions | 1430 x 1000 x 2000 mm (length x width x height) |



Devices at work

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Layout

